

IFW
AF/1762



AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROSECUTION - GROUP ART UNIT 1762

03500.016291.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Marianne L. Padgett
RYUJI BIRO, ET AL.)	
	:	Group Art Unit: 1762
Application No.: 10/098,569)	
	:	
Filed: March 18, 2002)	
	:	
For: VACUUM DEPOSITION)	
SYSTEM AND THIN-FILM :	:	
DEPOSITION PROCESS)	June 30, 2004

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

a) Introductory Comments

In response to the final Office Action dated April 1, 2004, kindly amend the
subject application under 37 C.F.R. § 1.116 as follows: